

ABSTRACT OF THE DISCLOSURE

An apparatus for detecting an amount of strain comprises a strain generating part, an electrical insulating layer and sensing elements. The strain generating part is a member to which strain is to
5 be applied. The electrical insulating layer is formed on the strain generating part. The sensing elements are formed on the electrical insulating layer. Each of the sensing elements is made of a silicon film. The silicon film comprises a poly-crystalline main layer and a poly-crystalline interface-layer, which comes into contact with the
10 electrical insulating layer.